

# Stanislav Jurecka

## List of Publications by Year in descending order

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Version: 2024-02-01

30  
papers

292  
citations

1163117

8  
h-index

888059

17  
g-index

31  
all docs

31  
docs citations

31  
times ranked

183  
citing authors

| #  | ARTICLE   | IF  | CITATIONS |
|----|---|-----|-----------|
| 1  | Microstructure and optical properties of etched silicon layers for photovoltaic applications. , 2022, , .   |     | 0         |
| 2  | Effect of annealing on the micromorphology and corrosion properties of Ti/SS thin films. Superlattices and Microstructures, 2020, 146, 106681.  | 3.1 | 29        |
| 3  | Multifractal and optical bandgap characterization of Ta <sub>2</sub> O <sub>5</sub> thin films deposited by electron gun method. Optical and Quantum Electronics, 2020, 52, 1.                            | 3.3 | 46        |
| 4  | Microstructure and optical properties of layers formed by anodic etching of silicon. AIP Conference Proceedings, 2019, , .  | 0.4 | 1         |
| 5  | Determination of thickness of electrochemically etched Si layers passivated by Si <sub>3</sub> N <sub>4</sub> by analysis of the experimental spectral reflectance. AIP Conference Proceedings, 2019, , . | 0.4 | 1         |
| 6  | Minkowski functional characterization and fractal analysis of surfaces of titanium nitride films. Materials Research Express, 2019, 6, 086463.  | 1.6 | 126       |
| 7  | Prepared ĩf-MnO <sub>2</sub> thin films by chemical bath deposition methods and study of its optical and microstructure properties. Optical and Quantum Electronics, 2019, 51, 1.                         | 3.3 | 10        |
| 8  | Thickness and tensile stress determination of black silicon layers by spectral reflectance and Raman scattering. Journal of Electrical Engineering, 2019, 70, 51-57.                                      | 0.7 | 1         |
| 9  | Black silicon â€œ correlation between microstructure and Raman scattering. Journal of Electrical Engineering, 2019, 70, 58-64.  | 0.7 | 0         |
| 10 | Investigation of morphological and optical properties of nanostructured layers formed by the SSCT etching of silicon. Applied Surface Science, 2018, 461, 72-77.  | 6.1 | 1         |
| 11 | Properties of nanostructured layers formed on silicon. AIP Conference Proceedings, 2018, , .  | 0.4 | 0         |
| 12 | Microstructure and optical properties of black silicon layers. , 2018, , .  |     | 0         |
| 13 | Multifractal analysis and optical properties of nanostructured silicon layers. Applied Surface Science, 2017, 395, 150-156.   | 6.1 | 12        |
| 14 | Properties of nanocrystalline Si layers embedded in structure of solar cell. Journal of Electrical Engineering, 2017, 68, 48-52.  | 0.7 | 0         |
| 15 | Reflectance analysis of porosity gradient in nanostructured silicon layers. , 2017, , .   |     | 0         |
| 16 | Statistical and Fractal Analysis of Random Height Function. Communications - Scientific Letters of the University of Zilina, 2017, 19, 57-61.   | 0.6 | 0         |
| 17 | Analysis of linear and nonlinear effects in optical fiber. , 2016, , .  |     | 0         |
| 18 | Multifractal analysis of textured silicon surfaces. Applied Surface Science, 2014, 301, 46-50.  | 6.1 | 18        |

| #  | ARTICLE  | IF  | CITATIONS |
|----|--|-----|-----------|
| 19 | Measuring capacitance of various types of structures. , 2014, , .  |     | 3         |
| 20 | Passivation of Si-based structures in HCN and KCN solutions. Applied Surface Science, 2012, 258, 8397-8405.  | 6.1 | 9         |
| 21 | Properties of charge states in MOS structure with ultrathin oxide layer. Applied Surface Science, 2012, 258, 8409-8414.  | 6.1 | 3         |
| 22 | Study of density of interface states in MOS structure with ultrathin NAOS oxide. Open Physics, 2012, 10, .   | 1.7 | 4         |
| 23 | The cavity resonator design: stochastic optimization of the transmission line method. Proceedings of SPIE, 2011, , .   | 0.8 | 0         |
| 24 | Study of microstructural and optical properties of a-Si:H thin films. , 2010, , .  |     | 1         |
| 25 | On the influence of the surface roughness onto the ultrathin SiO <sub>2</sub> /Si structure properties. Applied Surface Science, 2010, 256, 5623-5628.                           | 6.1 | 12        |
| 26 | On Topographic Properties of Semiconductor Surfaces and Thin Film Systems. Materials Science Forum, 2009, 609, 275-279.  | 0.3 | 3         |
| 27 | On determination of properties of ultrathin and very thin silicon oxide layers by FTIR and X - ray reflectivity. Materials Research Society Symposia Proceedings, 2008, 1066, 1. | 0.1 | 2         |
| 28 | Structural Characterization of Iron in Human Spleen. Materials Research Society Symposia Proceedings, 2008, 1132, 1.   | 0.1 | 2         |
| 29 | On formation of thin SiO <sub>2</sub> /a-Si:H interface when biased oxidized semiconductor surface interacts with plasma or liquid solution. Open Physics, 2007, 5, .            | 1.7 | 1         |
| 30 | <title>Investigation of electrical, structural, and optical properties of very thin oxide/a-Si:H/c-Si interfaces passivated by cyanide treatment</title>. , 2004, 5774, 481.     |     | 1         |